

J
10/58
AP20 Rec'd PCT/PTO 01 AUG

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Kenichi SHIRAISHI

Application No.: New U.S. National Phase of PCT/JP2005/001827

Filed: August 1, 2006

Docket No.: 128985

For: EXPOSURE APPARATUS, DEVICE MANUFACTURING METHOD,
MAINTENANCE METHOD, AND EXPOSURE METHOD

PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Please consider the following:

Amendments to the Specification; and

Remarks.